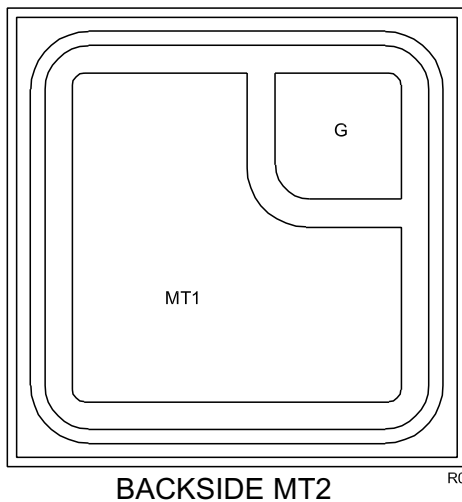


**PROCESS DETAILS**

Process	GLASS PASSIVATED MESA
Die Size	130 MILS x 130 MILS
Die Thickness	8.6 MILS ± 0.6 MILS
MT1 Bonding Pad Area	99 MILS x 49 MILS
Gate Bonding Pad Area	34 MILS x 34 MILS
Top Side Metalization	Al - 45,000Å
Back Side Metalization	Al/Mo/Ni/Ag - 32,000Å

**GEOMETRY**



**GROSS DIE PER 4 INCH WAFER**

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**PRINCIPAL DEVICE TYPES**

CQ220-12B Series  
CQDD-12M Series

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